

Form PTO-1449 (REV 8-83)	DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	SERIAL NO. Herewith	ATTY DOCKET NO. STL 11004.00
INFORMATION DISCLOSURE CITATION (USE SEVERAL SHEETS IF NECESSARY) PAGE 1 OF 1		APPLICANTS Ed F. Rejda et al.	
		FILING DATE Herewith	GROUP Not Yet Assigned

U.S. PATENT DOCUMENTS

E.I.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>Mr</i>	AA 4,549,238	10/22/85	Ertingshausen, et al	360	103	1/10/83
	AB 5,118,577	6/2/92	Brar et al	428	409	7/3/89
	AC 6,027,660	2/22/00	Hsiao et al	216	22	5/11/98
	AD 5,563,752	10/8/96	Komuro et al	360	113	9/8/94
	AE 5,883,770	3/16/99	Biskeborn et al	360	130.21	7/18/97
	AF 6,252,741 B1	6/26/01	Ahn, Junghi	360	235.1	5/11/99
	AG 6,199,267	3/13/01	Koshikawa et al	29	603.15	3/31/99
	AH 5,916,423	6/29/99	Westwood, John David	204	192.32	5/6/97
	AI 6,063,244	5/16/00	Pinarbasi, Mustafa	204	192.11	5/21/98
	AJ 6,197,164	3/6/01	Pinarbasi, Mustafa	204	192.11	10/10/97
	AK 6,335,063	1/1/02	Chen et al	427	558	10/20/99
	AL 6,170,149	1/9/01	Oshiki et al	29	603.09	1/30/97
<i>Mr</i>	AM 5,903,968	5/18/99	Shouji, Shigeru	29	603.09	3/23/95
	AN					
	AO					
	AP					
	AQ					
	AR					

FOREIGN PATENT DOCUMENTS

E.I.	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
	AS					

OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

<i>Mr</i>	AT	Diane K. Stewart, J. David Casey, Jr., <u>Handbook of Microlithography, Micromachining, and Microfabrication; Volume 2: Micromachining and Microfabrication</u> , Ch. 4, 153-195 (1999)
<i>Mr</i>	AU	P.E. Russell, T.J. Stark, D.P. Griffis, J.R. Phillips, and K.F. Jarausch, <u>Chemically and Geometrically Enhanced Focused Ion Beam Micromachining</u> , J. Vac. Sci. Technol. B 16(4), 2494-2498 (Jul/Aug 1998)
EXAMINER	<i>Podray McCarroll</i>	DATE CONSIDERED <i>8/9/05</i>

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.